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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number		Filed Herewith			
				Filing Date		November 17, 2003			
				First Named Inventor:		Thomas Hantschel			
				Examiner name: unknown		GROUP: unknown			
Sheet	1	of	1	Attorney Docket Number		A3235 (XCP-035)			
U.S. PUBLISHED PATENT APPLICATIONS									
Examiner Initials*	Cited No. ¹	U.S. Patent Document Number Kind Code ² (if known)		Name of Patentee or Applicant of Cited Document		Date of Publication of Cited Document MM-DD-YYYY		Pages, Columns, Lines Where Relevant Info. Appear	
	A01	5944537		Smith et al.		08/31/1999			
	A02	6183267		B1		Marcus et al.		02/06/2001	
	A03	6299462		B1		Bielgelsen		10/09/2001	
	A04	6352454		B1		Kim et al.		03/05/2002	
	A05	6582989		B2		Biegelsen et al.		06/24/2003	
U.S. PATENT DOCUMENTS									
Examiner Initials*	Cited No. ¹	U.S. Patent Document Number Kind Code ² (if known)		Name of Patentee or Applicant of Cited Document		Date of Publication of Cited Document MM-DD-YYYY		Pages, Columns, Lines Where Relevant Info. Appear	
FOREIGN PATENT DOCUMENTS									
Examiner Initials*	Cited No. ¹	Foreign Patent Document Office ³ Number ⁴ Kind Code ⁵ (if known)			Name of Patentee or Applicant of Cited Document		Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines Where Relevant Info. Appear	T ⁶
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)									
Despont et al.: "Wafer-Scale Microdevice Transfer/Interconnect: From A New Integration Method To Its Application In An AFM-Based Data-Storage System", 2003 IEEE, 12 th International Conference on Solid State Sensors, Actuators and Microsystems, Boston, June 8-12, 2003, pp. 1907-1910.									
Wada et al.: "Fine Pitch Micro Probe Tips Using Thin Film Amorphous Alloy Under The Micromachining Fabrication Technology, Advantest Laboratories Ltd., Precision and Intelligence Laboratories, Tokyo Institute of Technology, 6/6/2001.									
EXAMINER					DATE CONSIDERED				

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.